



**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Fumio KOYAMA et al.

Group Art Unit: 2812

Application No.: 10/801,821

Examiner: S. MULPURI

Filed: June 22, 2004

Docket No.: 111587.01

For: SURFACE EMITTING SEMICONDUCTOR  
LASER AND MANUFACTURING METHOD  
THEREOF

**MAIL STOP RCE**

**LARGE ENTITY REQUEST FOR  
CONTINUED EXAMINATION UNDER 37 C.F.R. §1.114**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. §1.114, Applicants hereby request continued examination.

☒ Applicants further request entry and consideration of the submission filed April 18, 2006.

The above-identified application was filed on or after June 8, 1995. Thus, entry is proper under 37 C.F.R. §1.114(d).

Attached hereto is our check no. 179989 in the amount of ☒ \$790.00 as payment of the fees set forth in 37 C.F.R. §1.17(e). The Commissioner is hereby authorized to charge any additional fees or credit any overpayment associated with this communication to Deposit Account No. 15-0461. Two duplicate copies of this page are enclosed.

Respectfully submitted,

James A. Oliff  
Registration No. 27,075

Tarik M. Nabi  
Registration No. 55,478

JAO:TMN/amw

Date: May 19, 2006

**OLIFF & BERRIDGE, PLC**  
**P.O. Box 19928**  
**Alexandria, Virginia 22320**  
**Telephone: (703) 836-6400**

DEPOSIT ACCOUNT USE  
AUTHORIZATION  
Please grant any extension  
necessary for entry;  
Charge any fee due to our  
Deposit Account No. 15-0461

05/22/2006 SZEWDIE1 00000000 10001021

01 FC:1001

790.00 0P